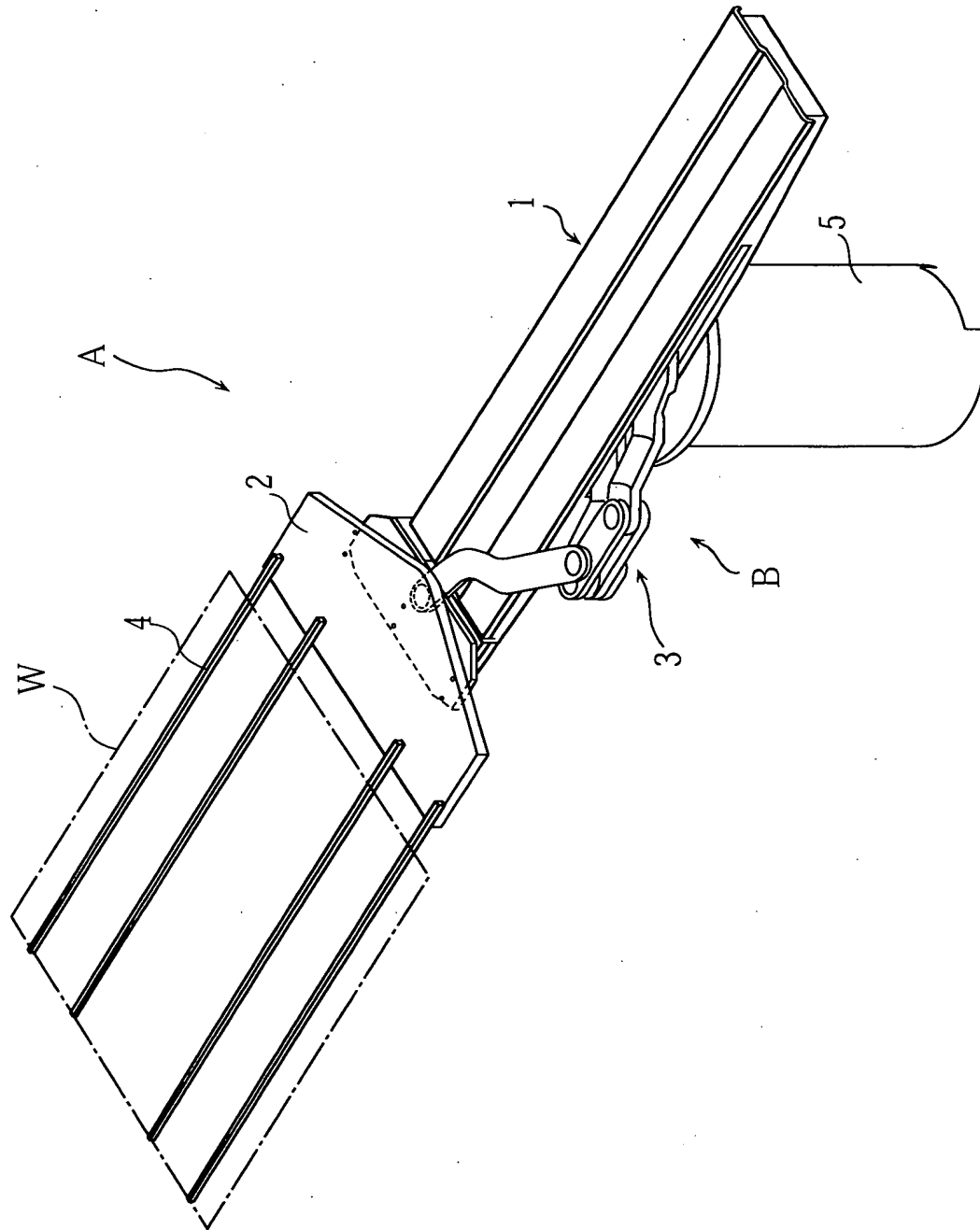
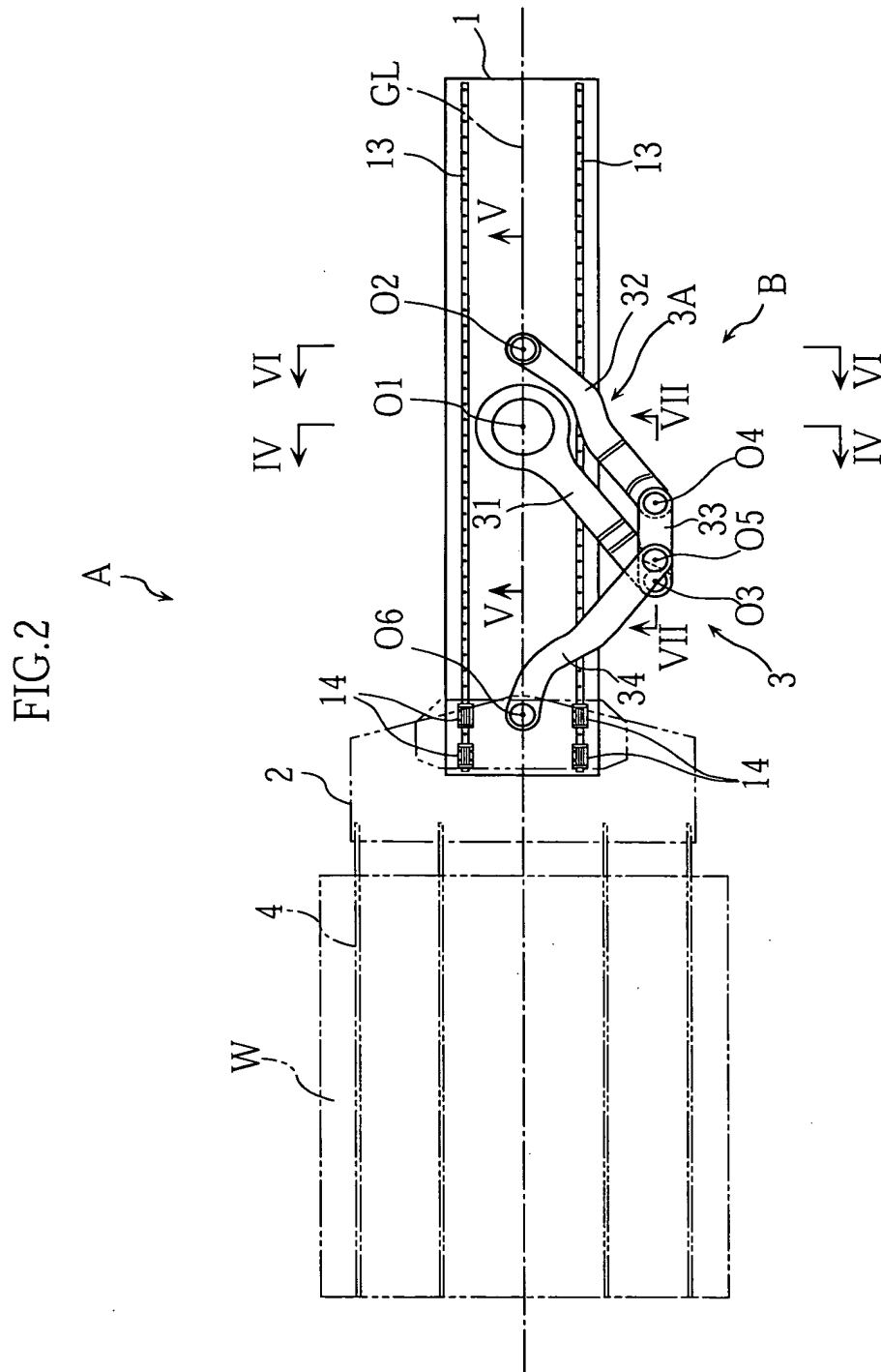


FIG.1





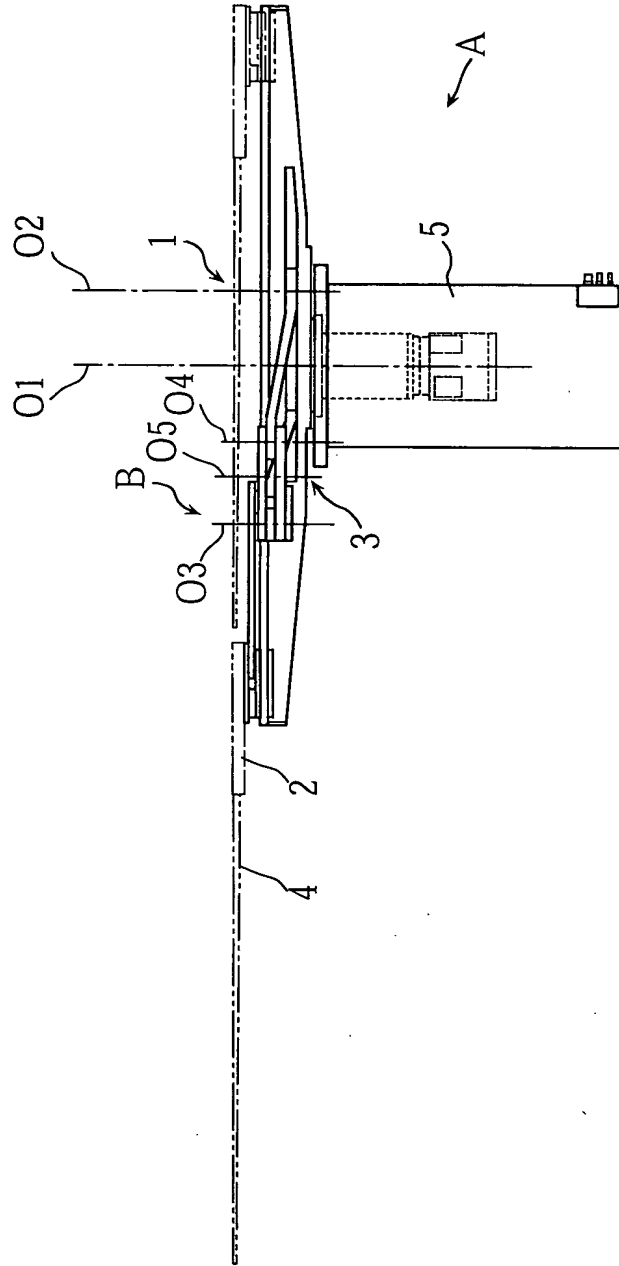


FIG. 3

FIG. 4

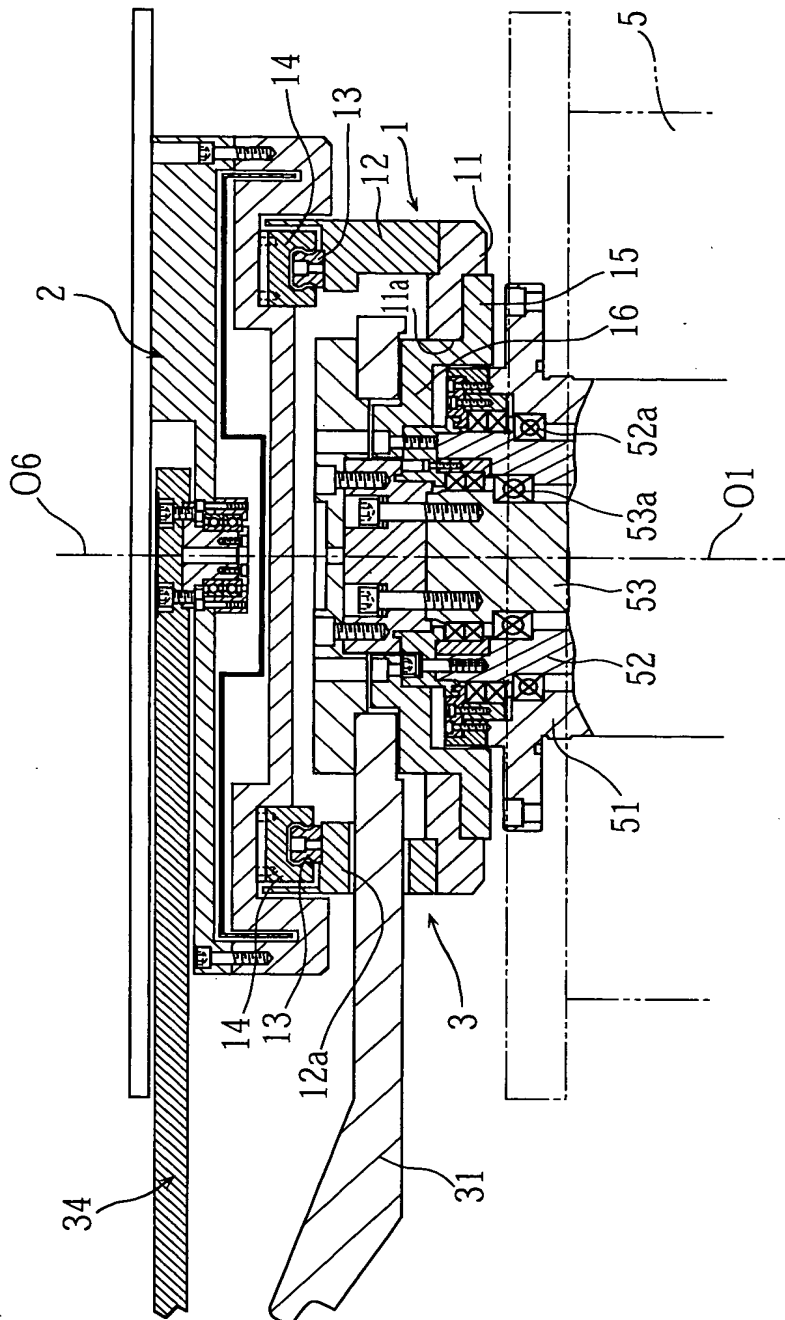
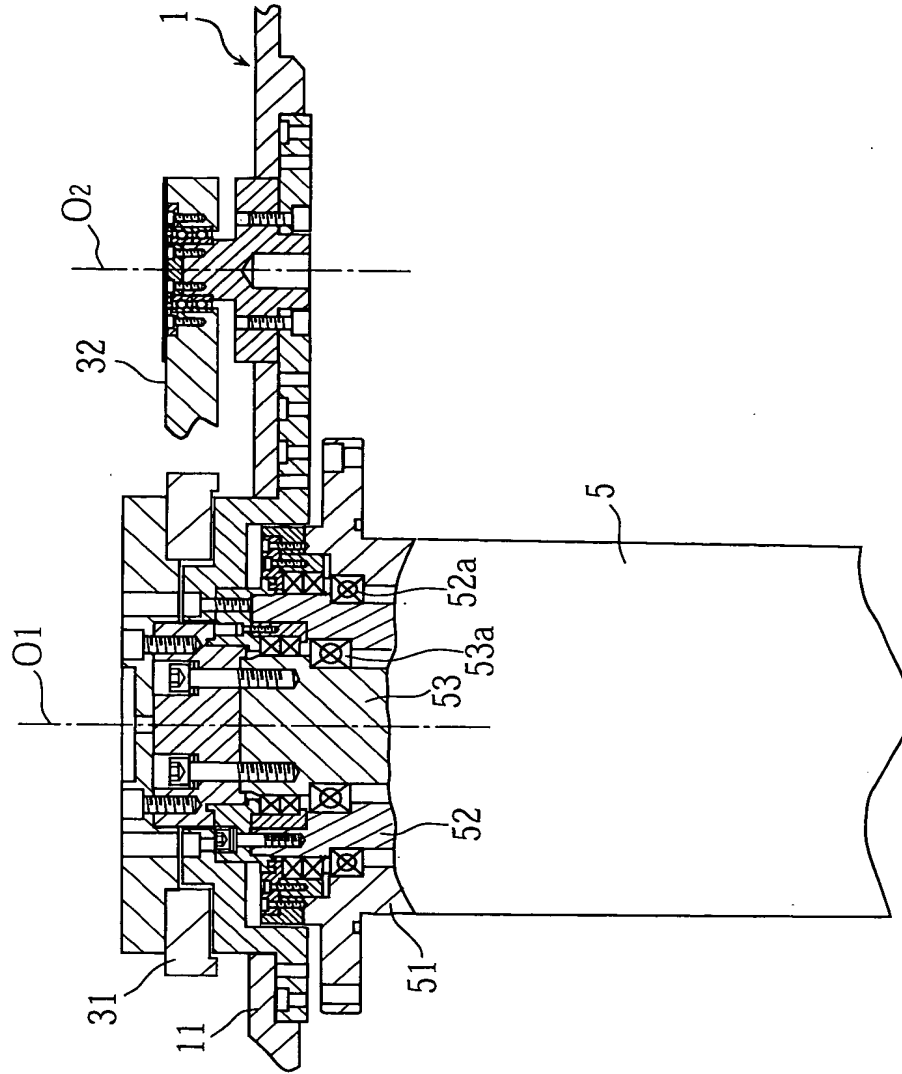


FIG.5



5



FIG. 7

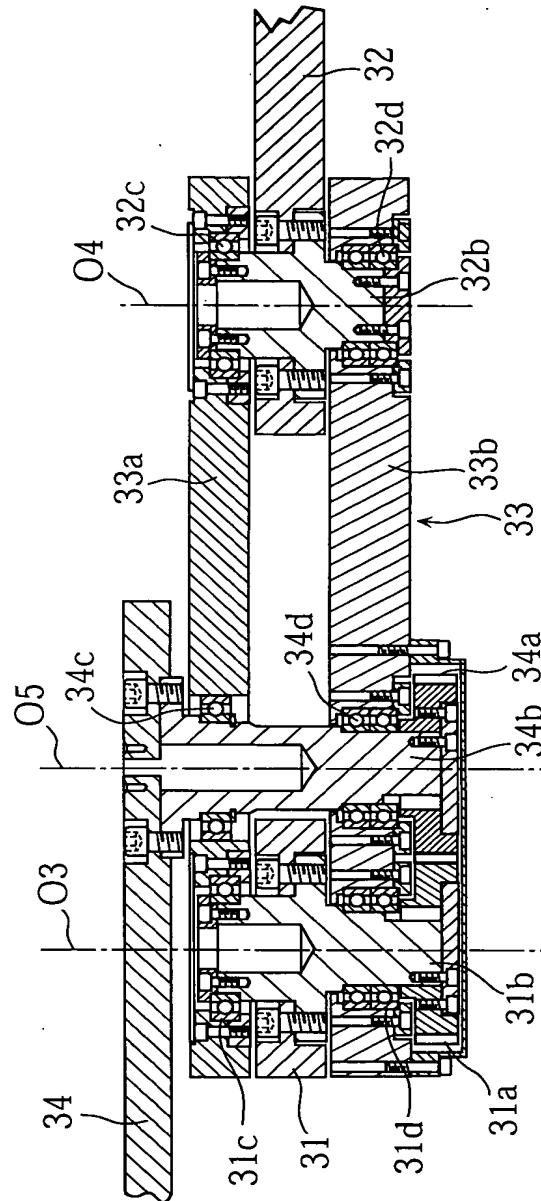


FIG. 8

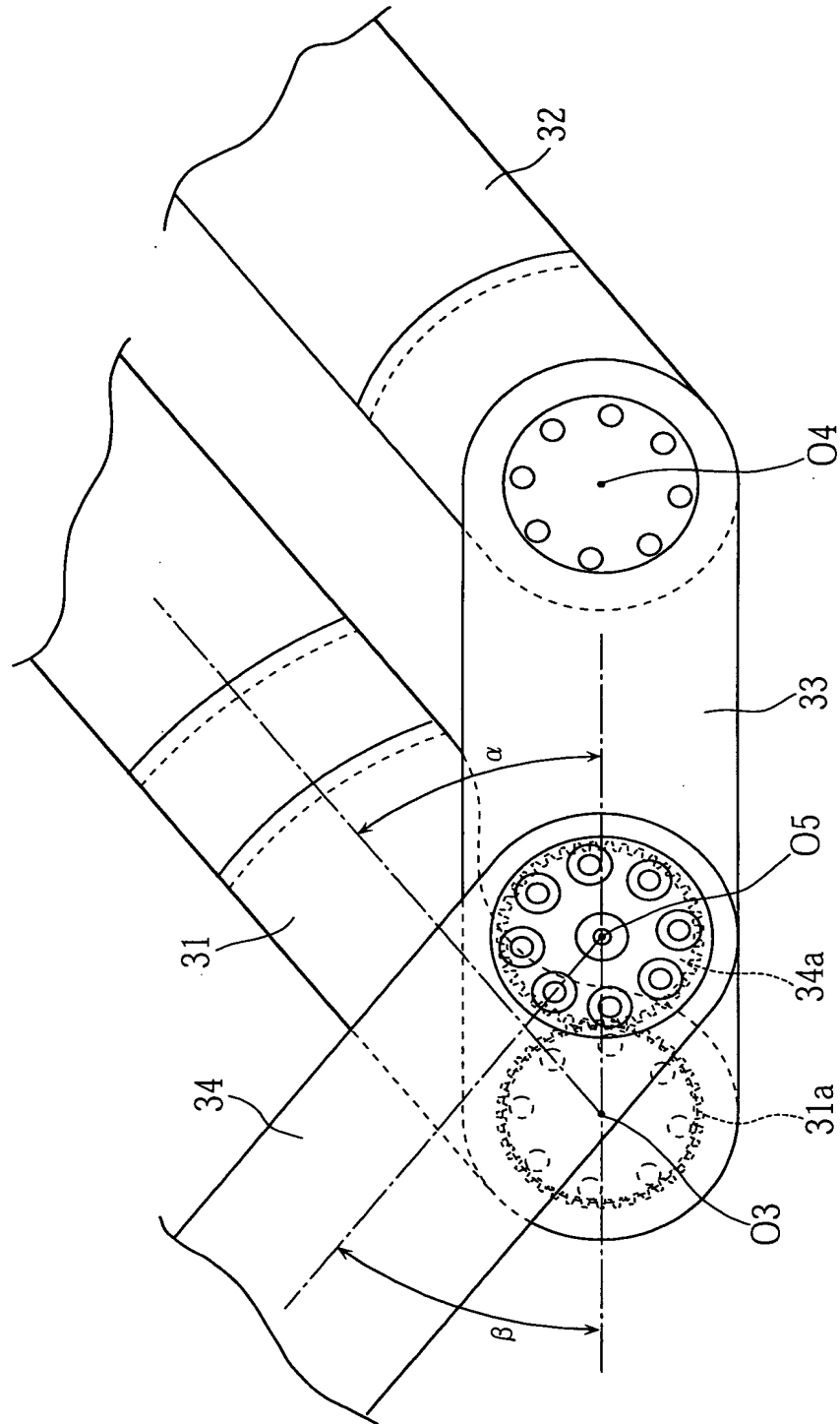




FIG. 9

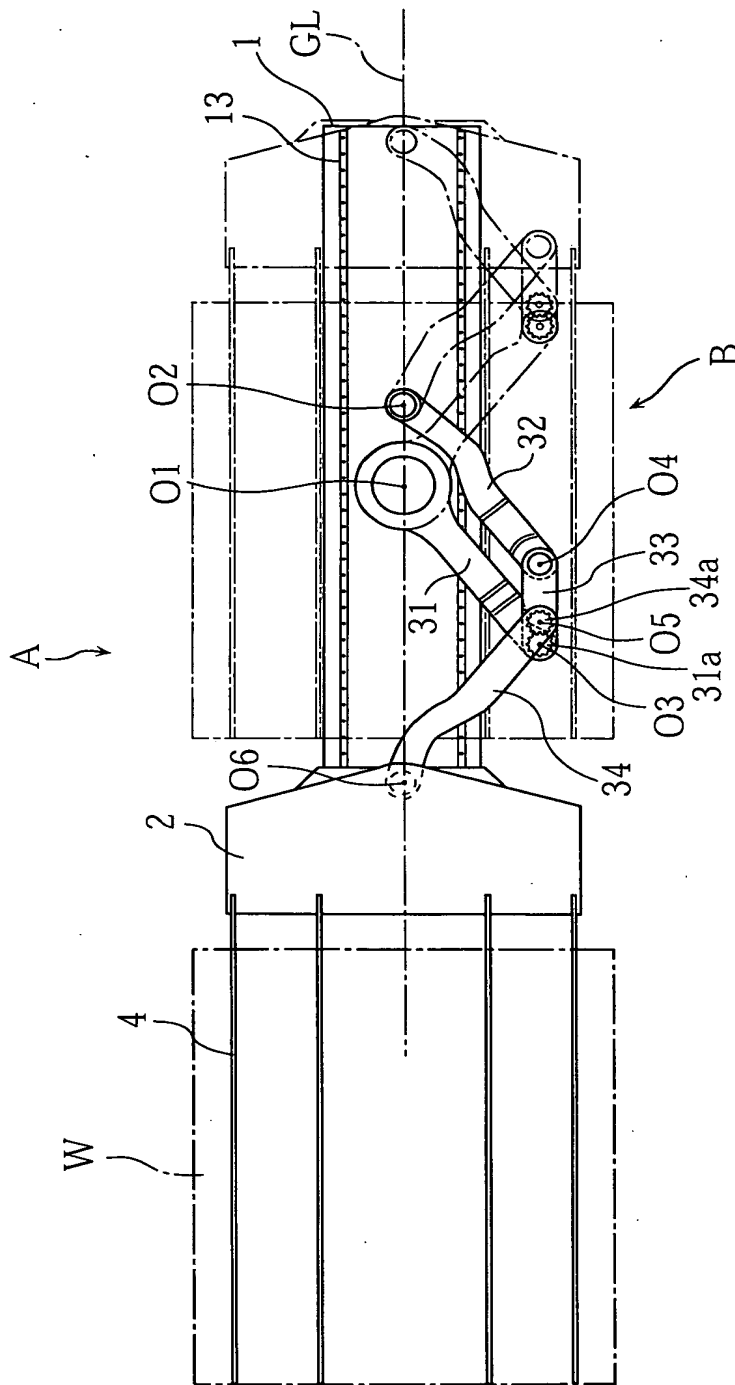


FIG.10

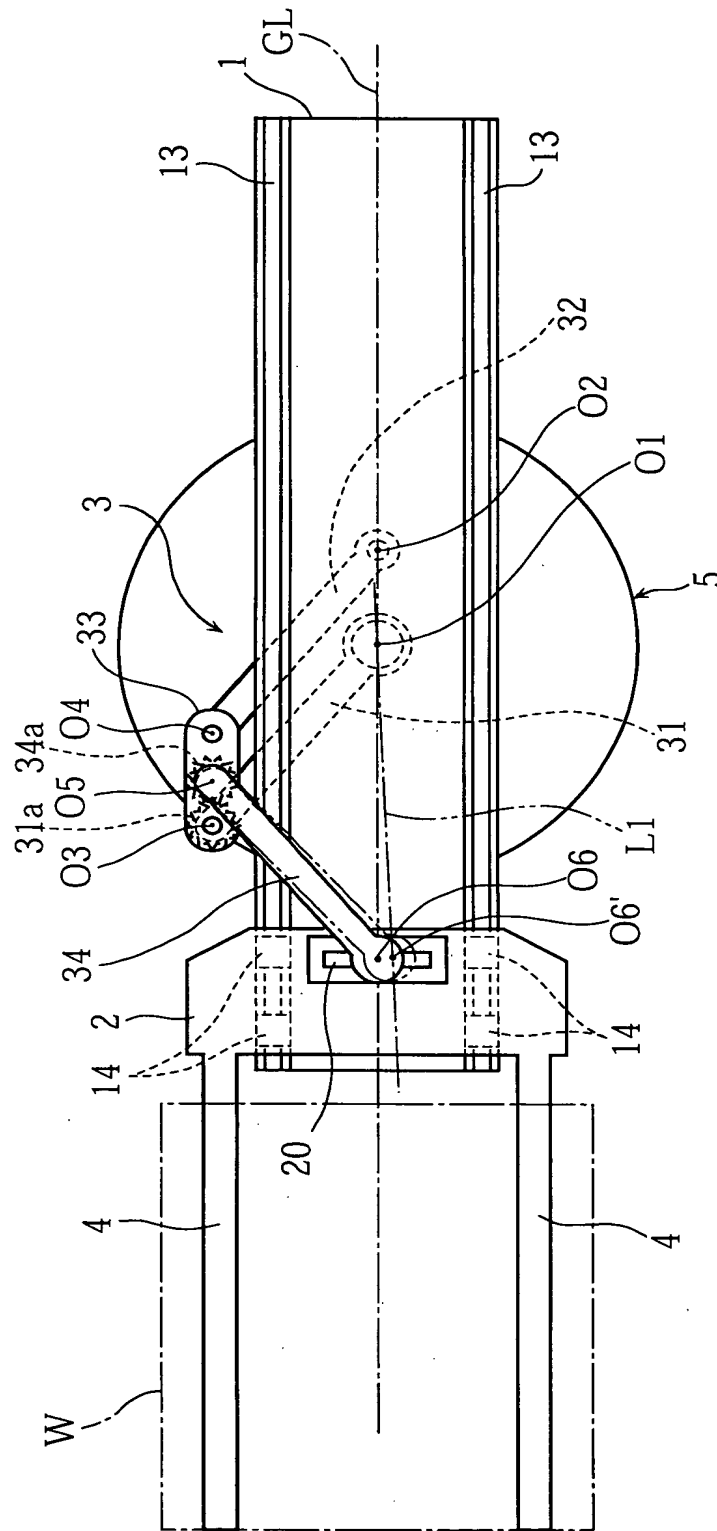


FIG.11

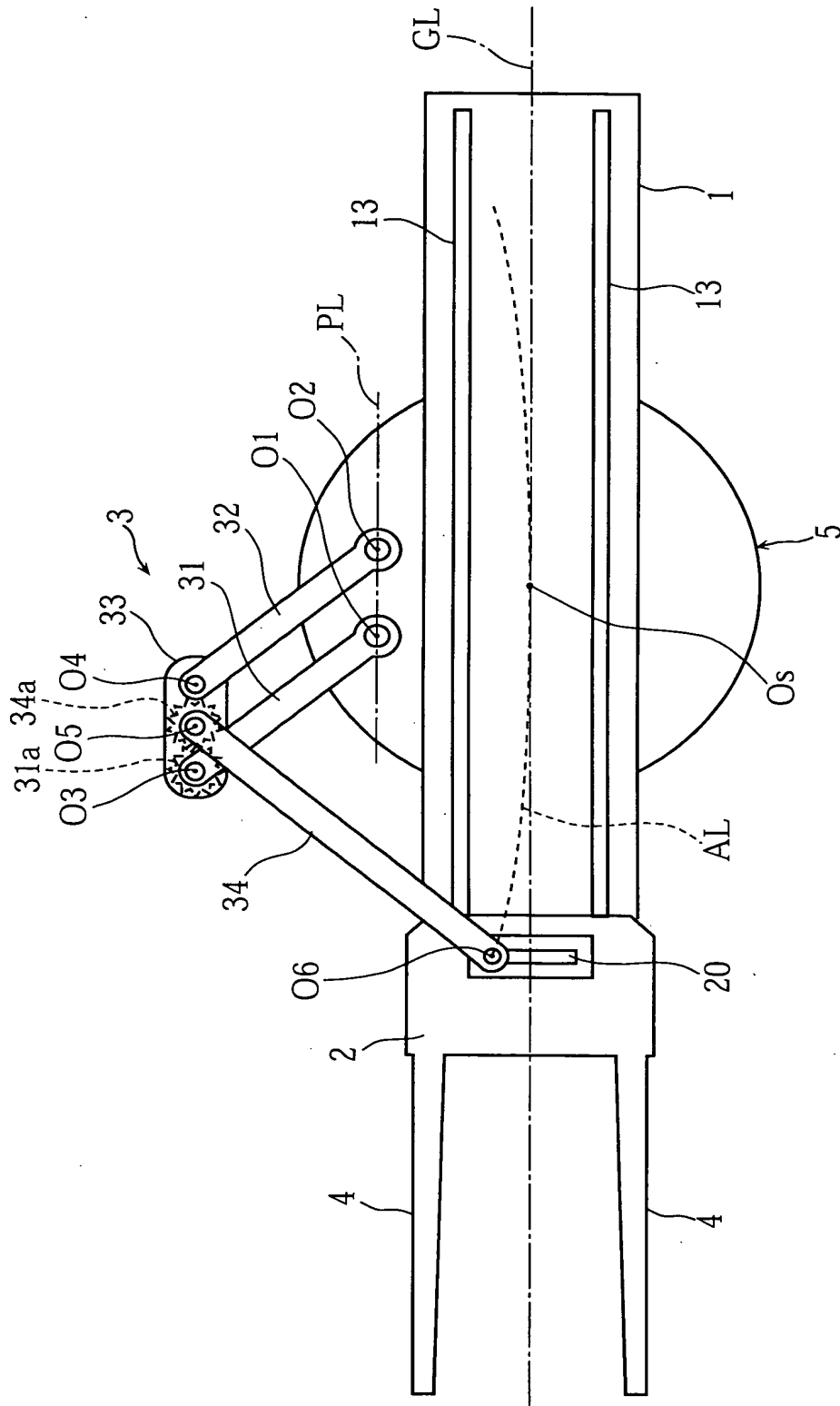


FIG. 12

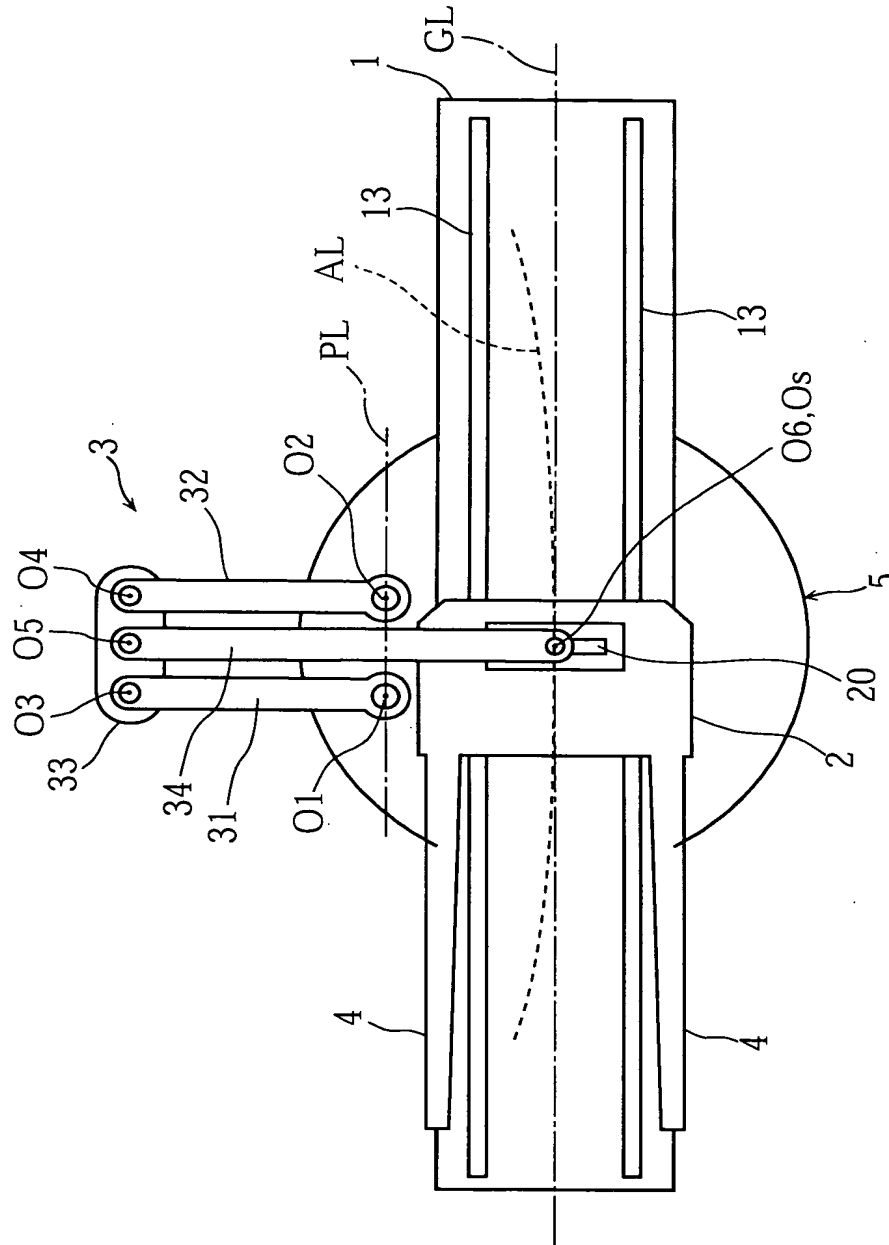


FIG.13

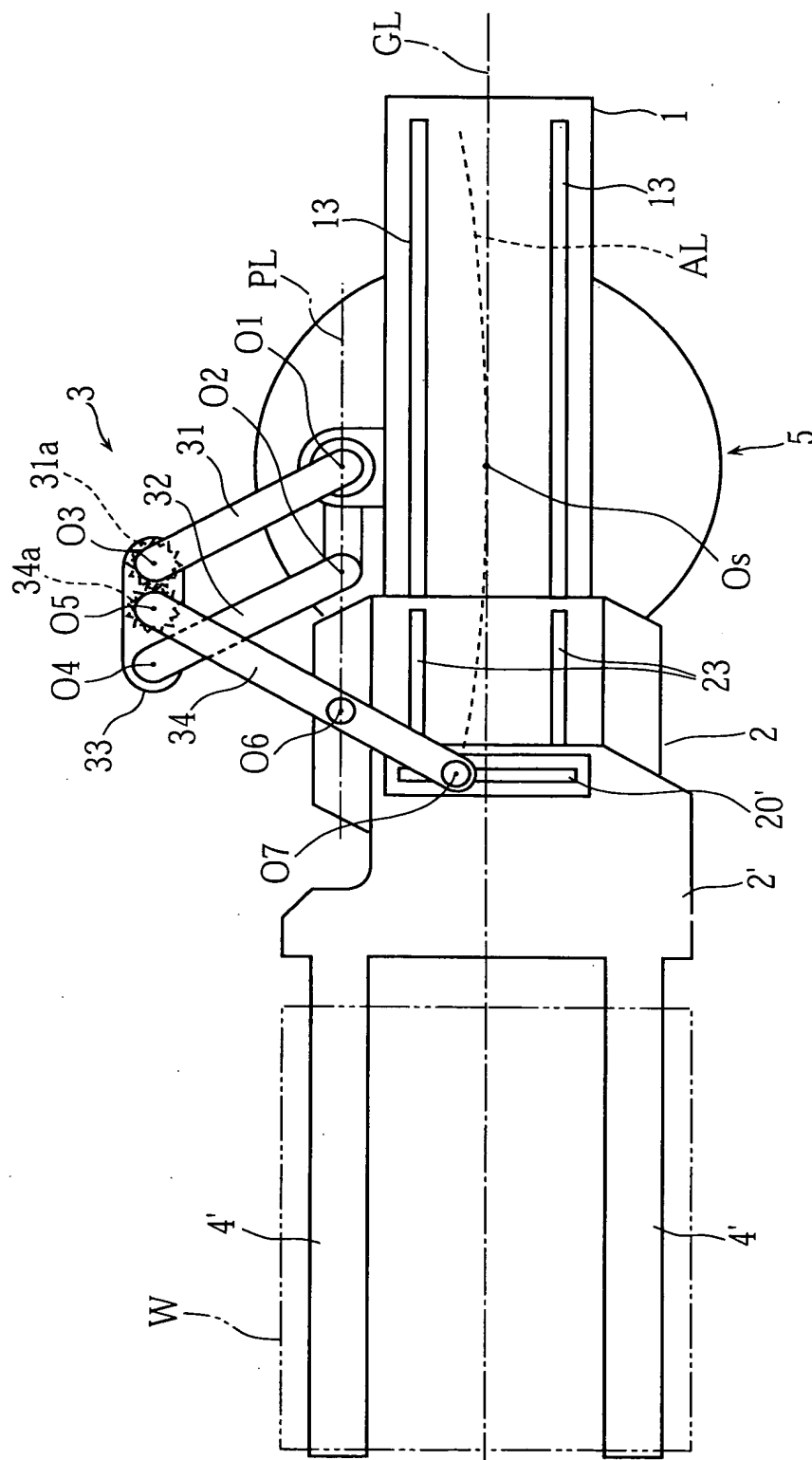
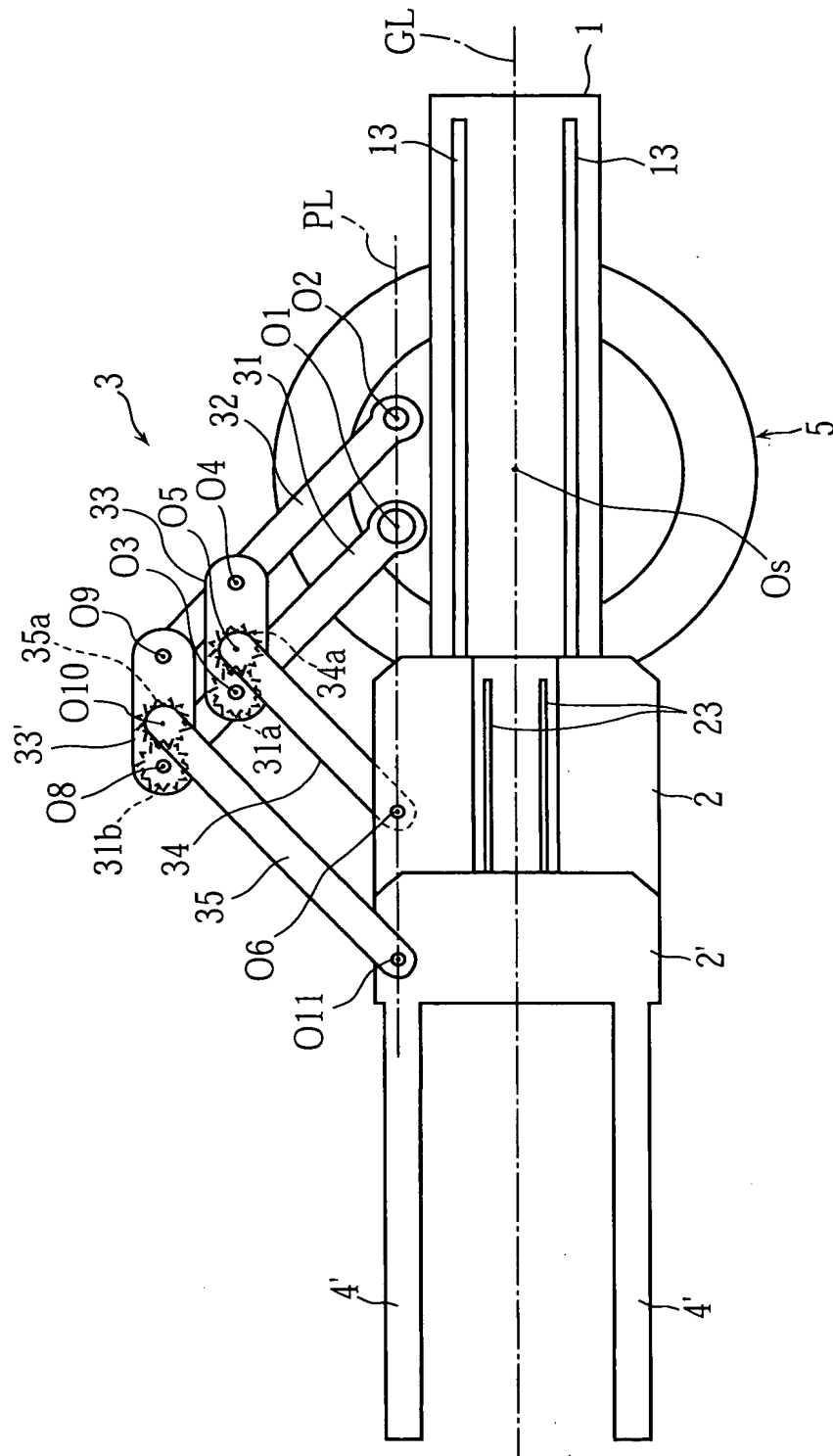
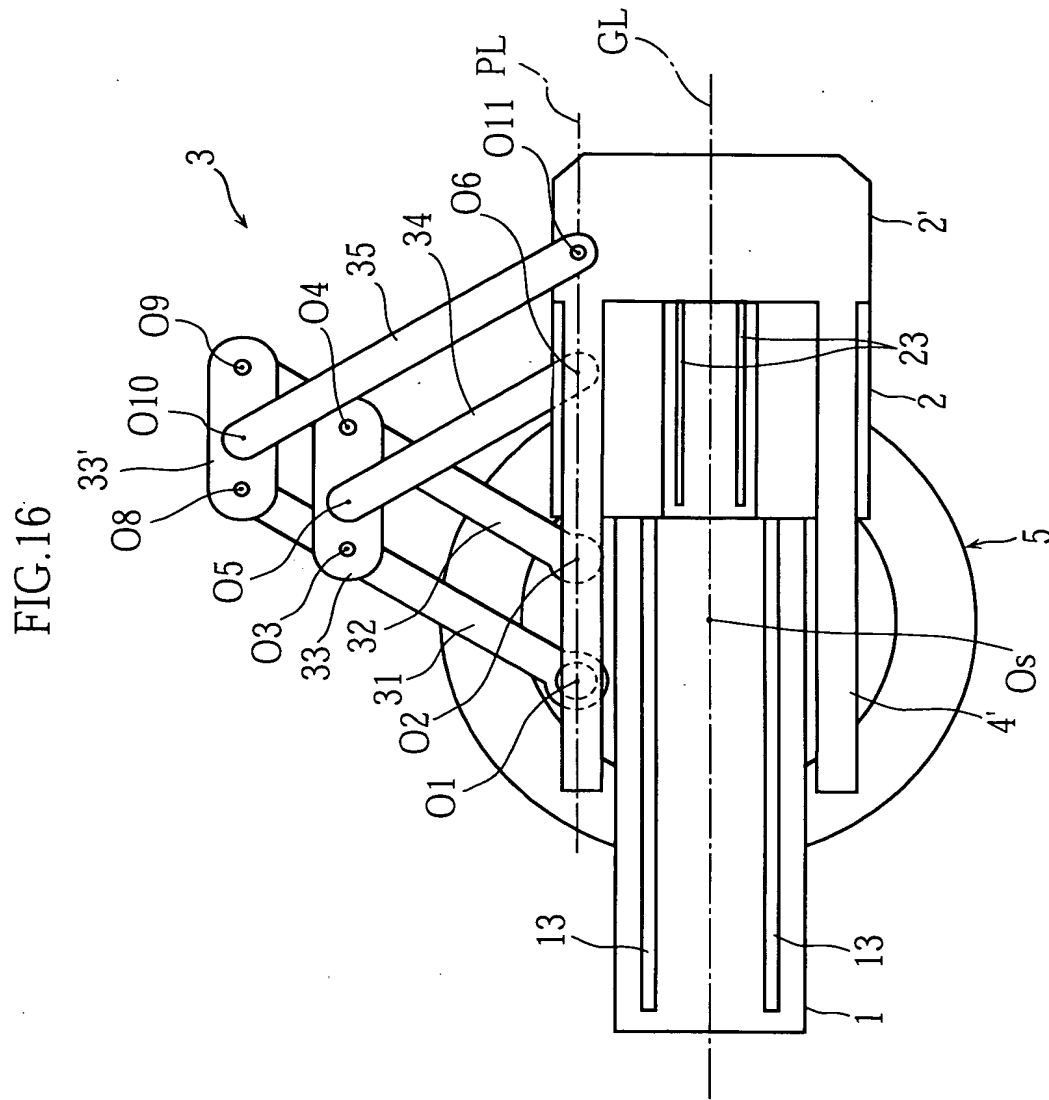


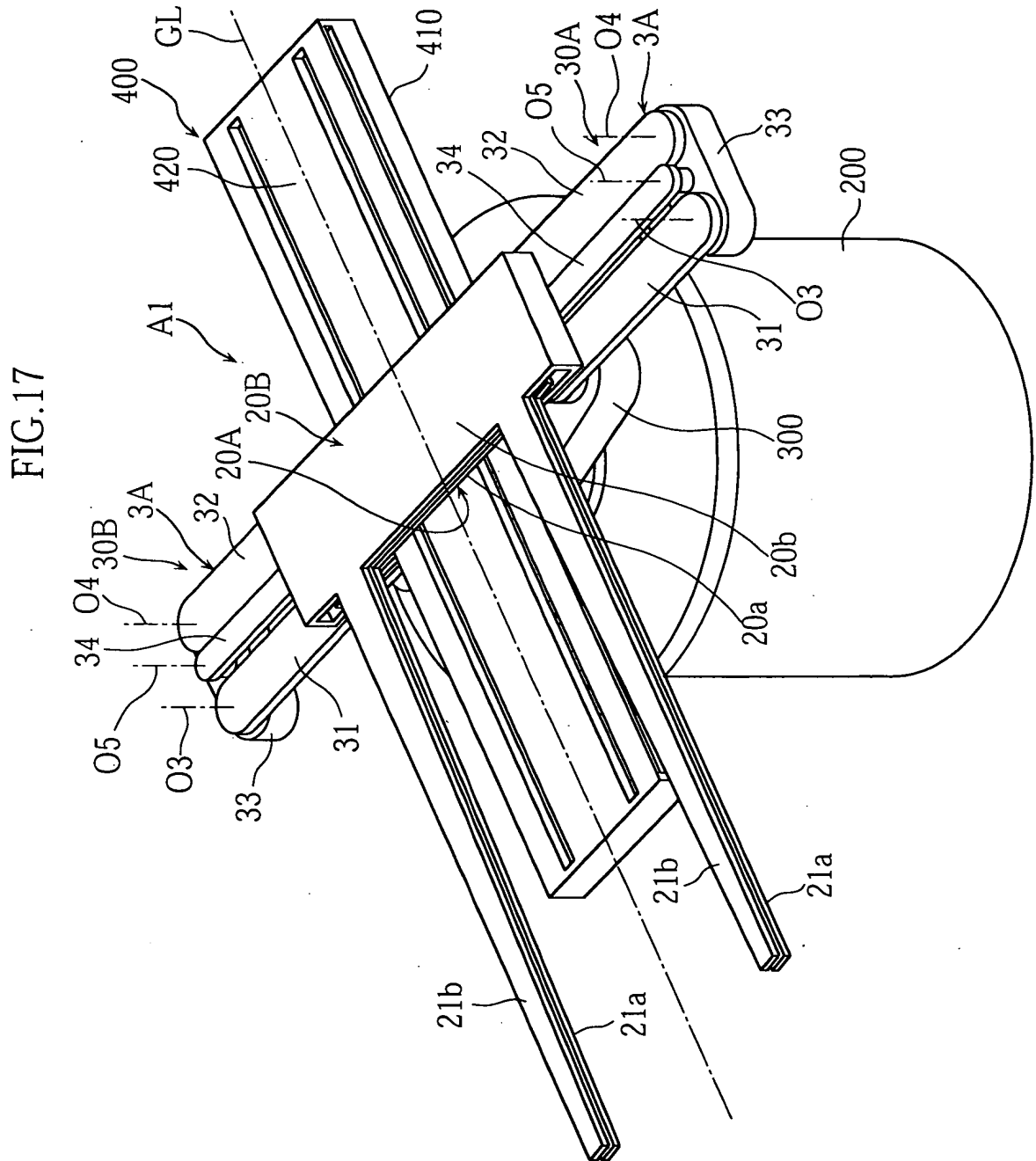


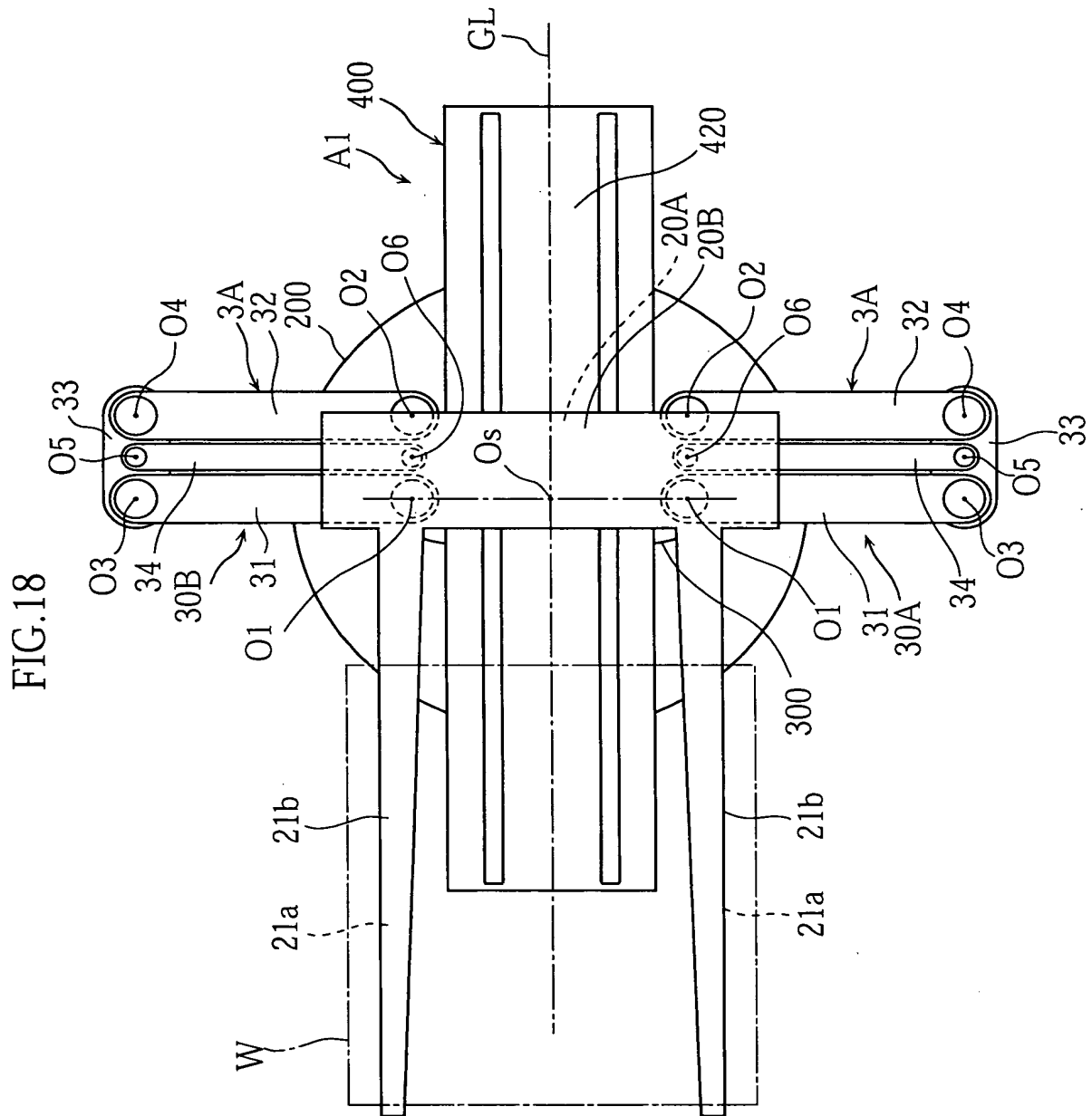
FIG.15

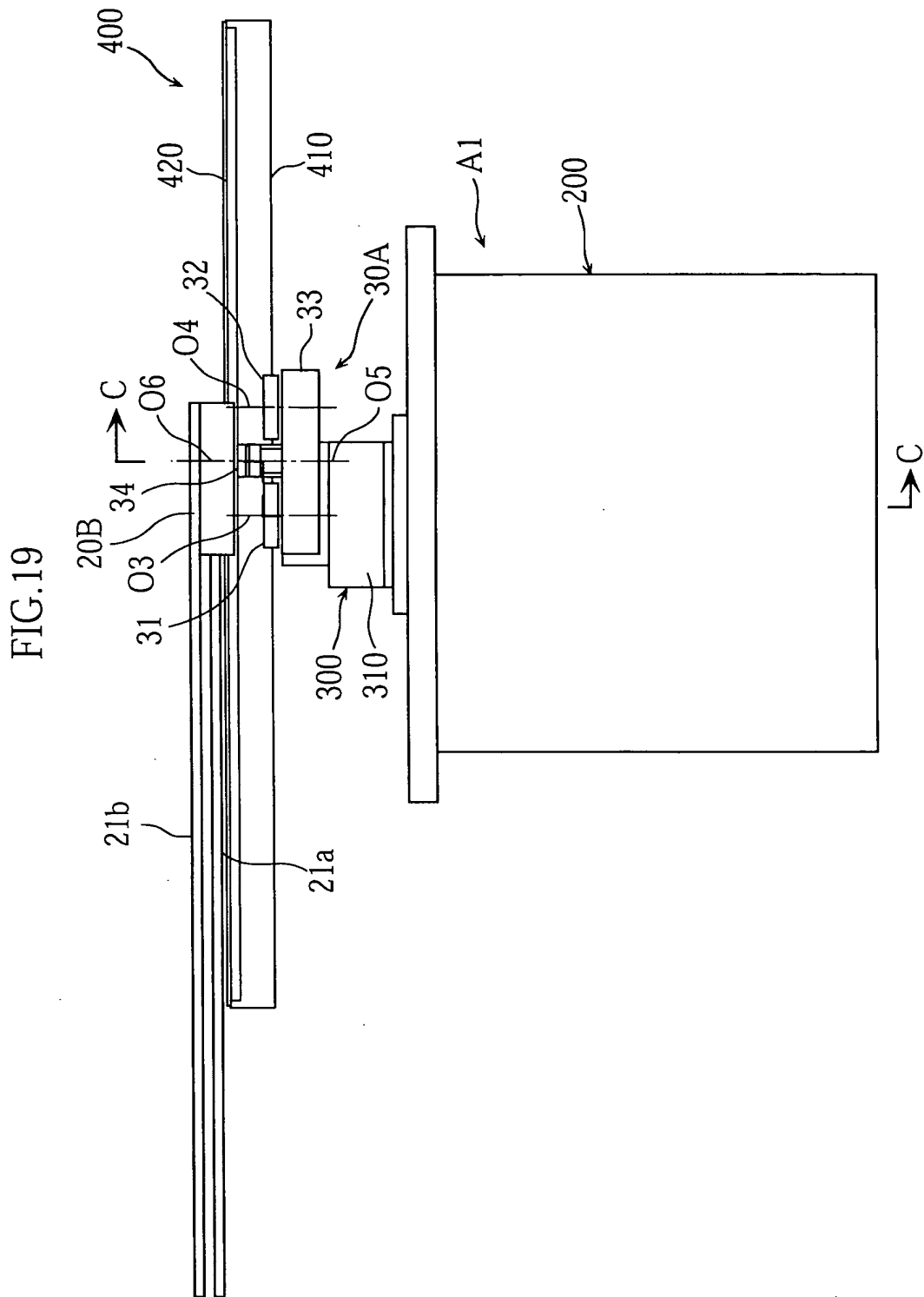












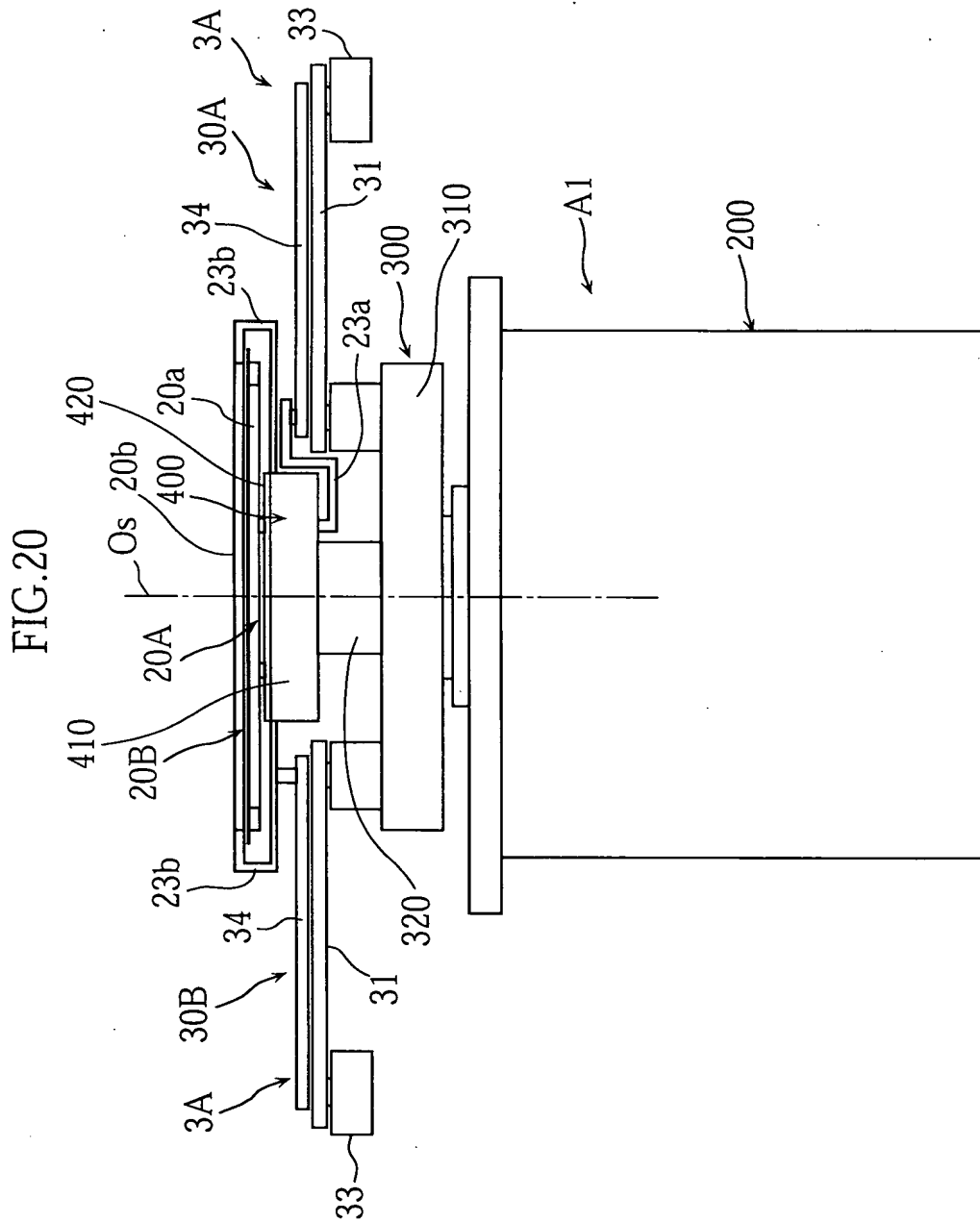


FIG. 21

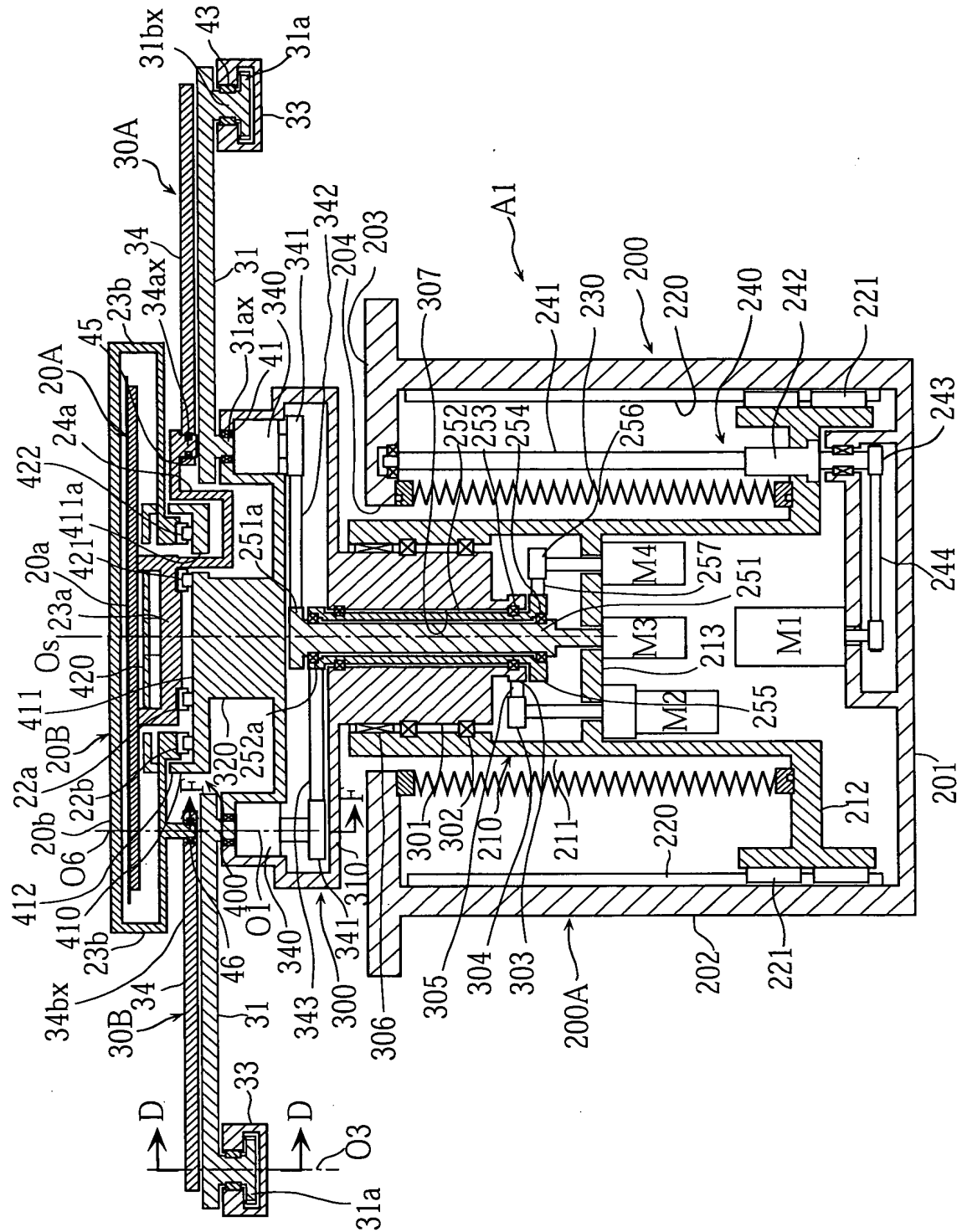


FIG.22

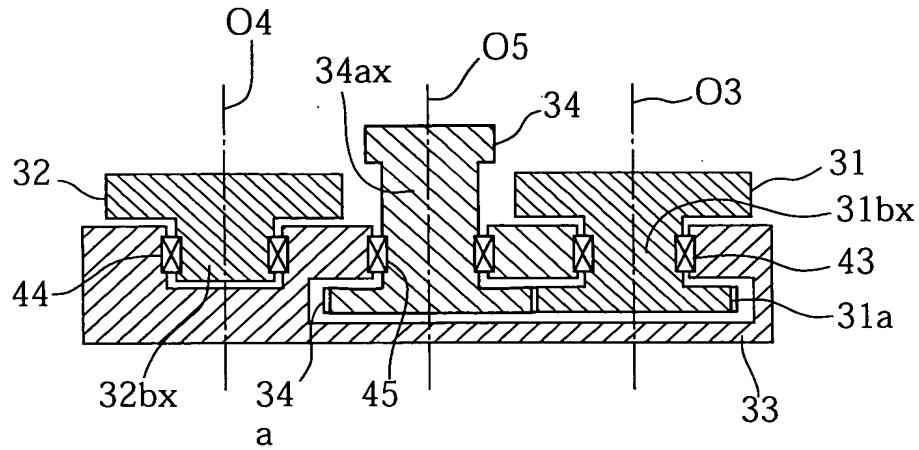


FIG.23

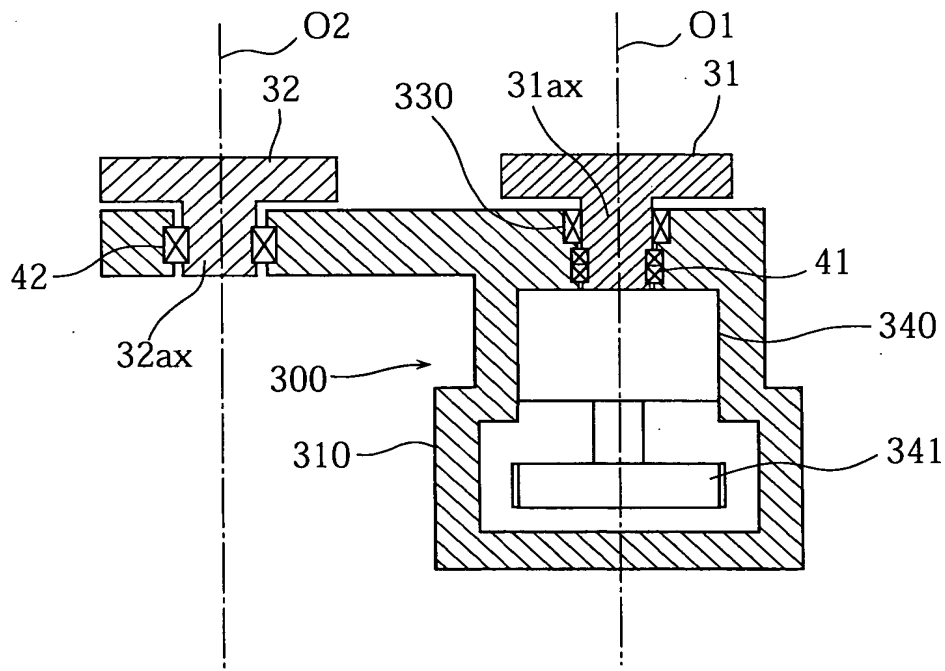
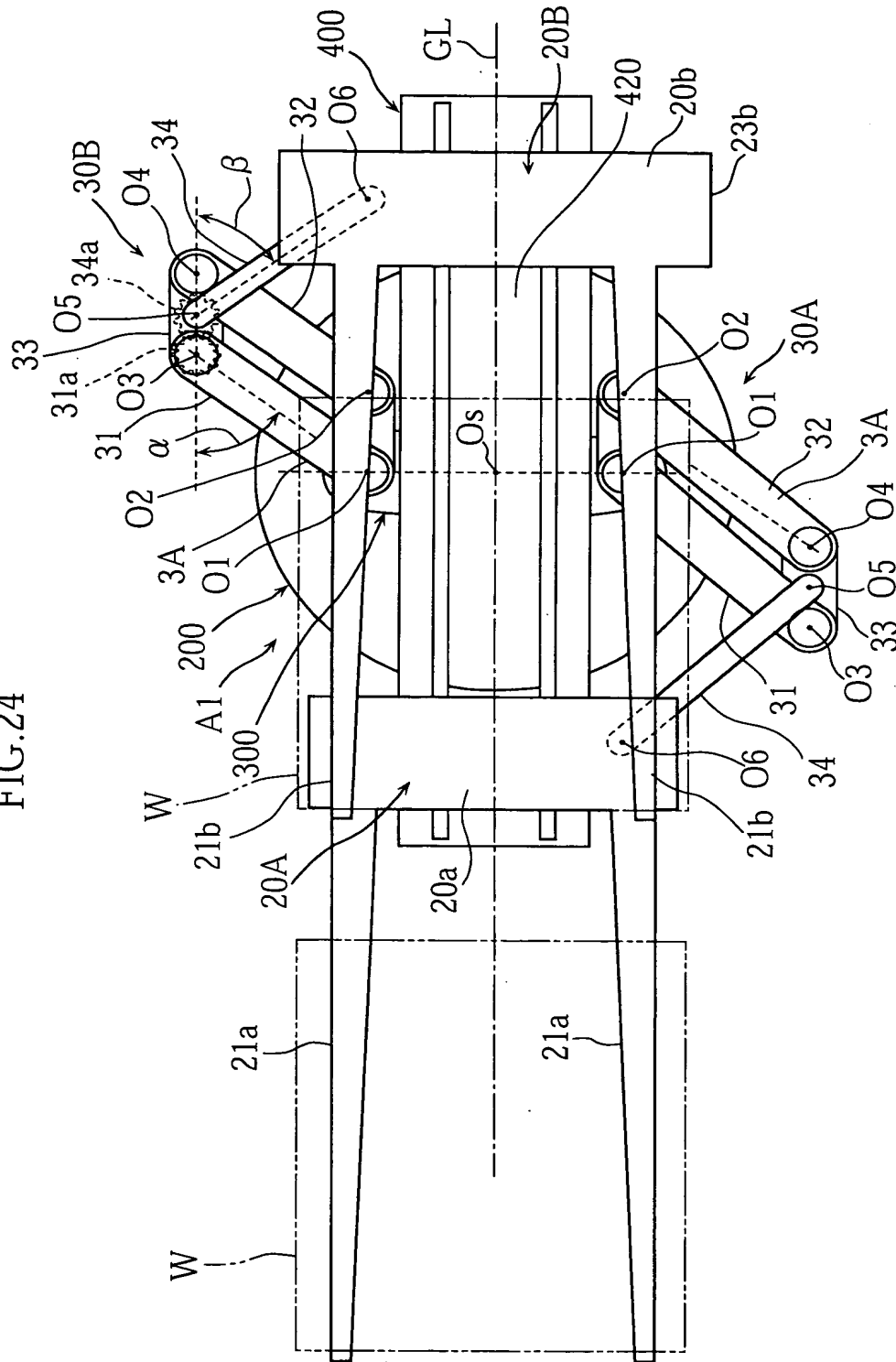
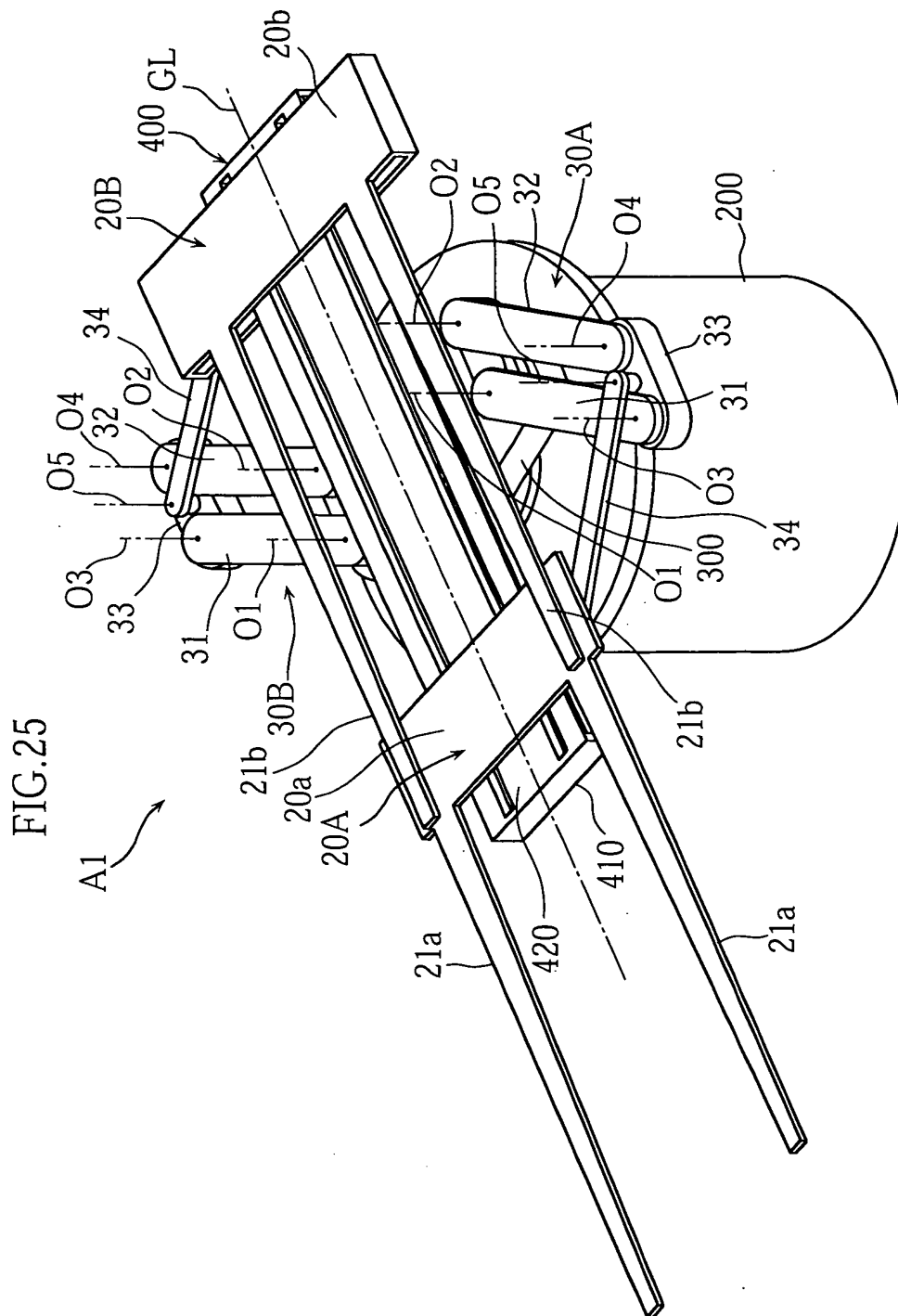
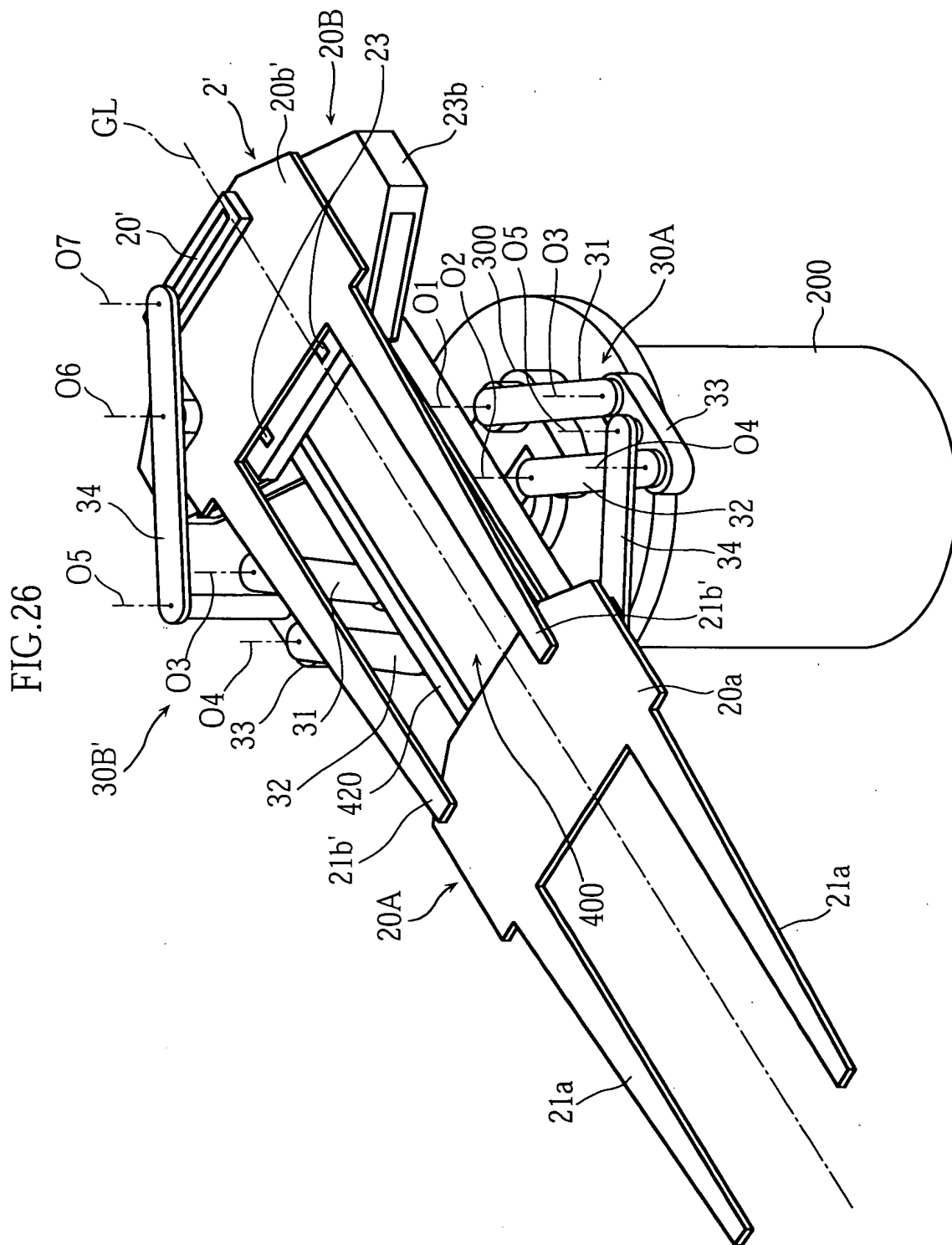


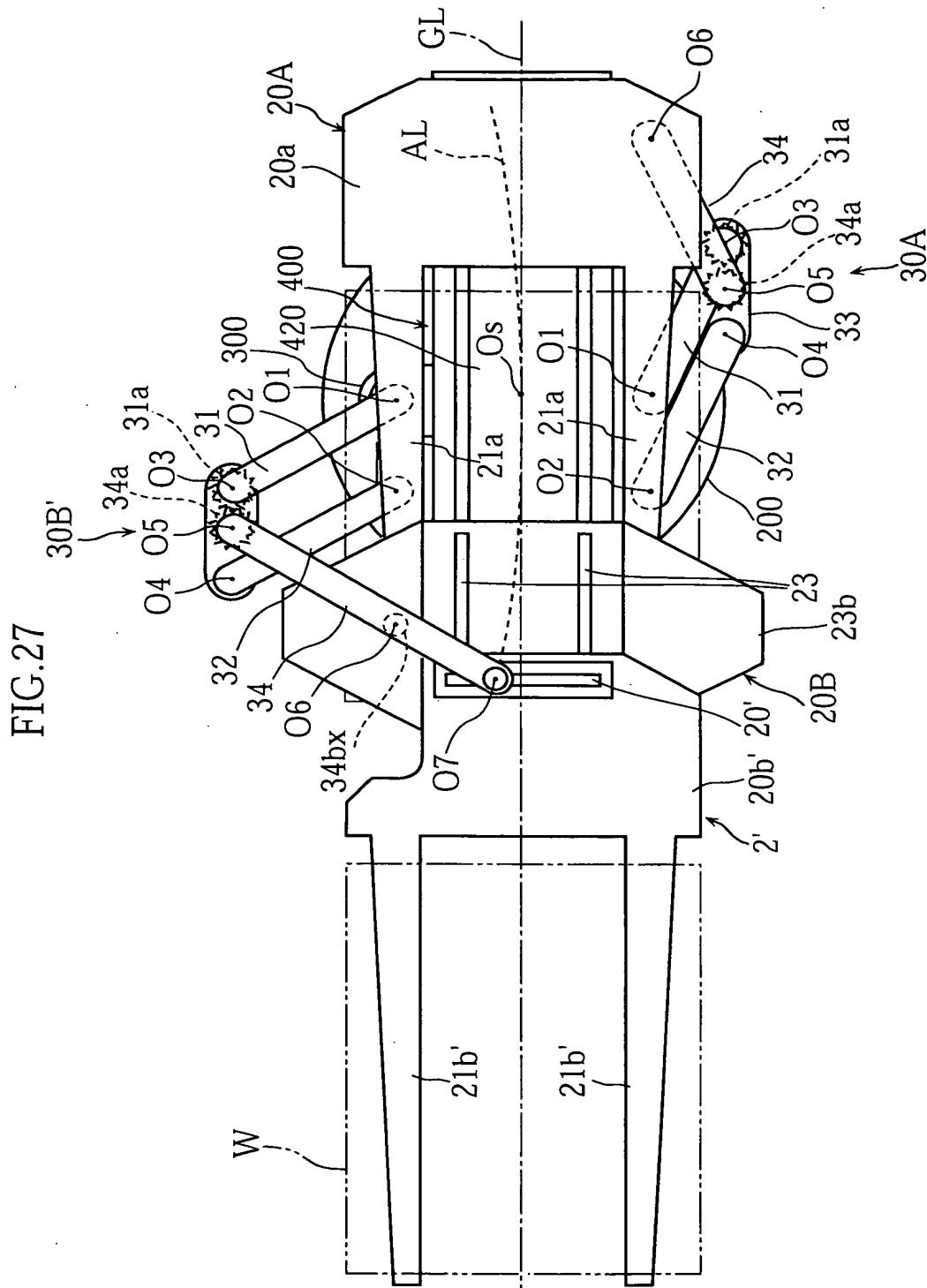
FIG. 24

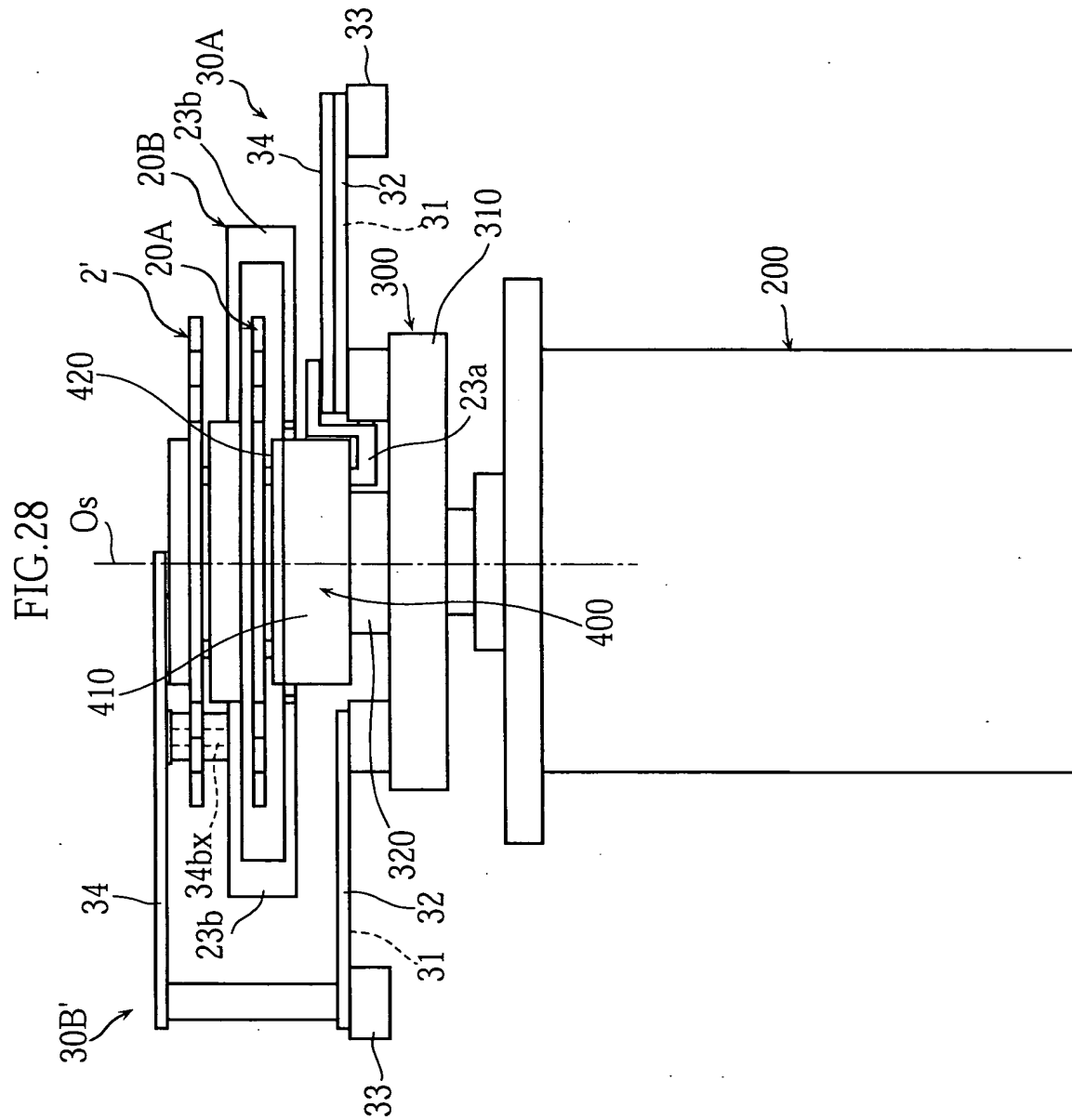












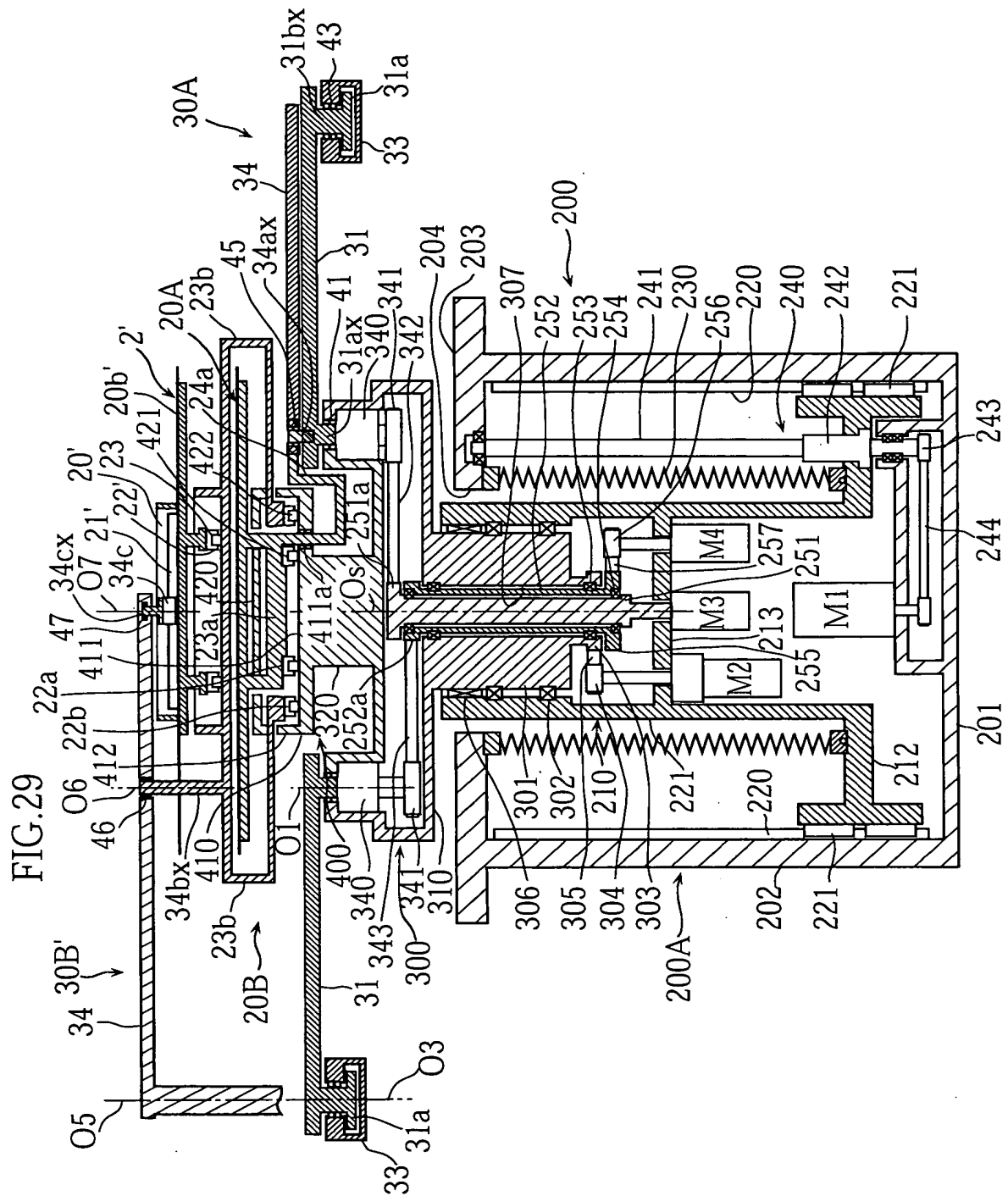


FIG.30A

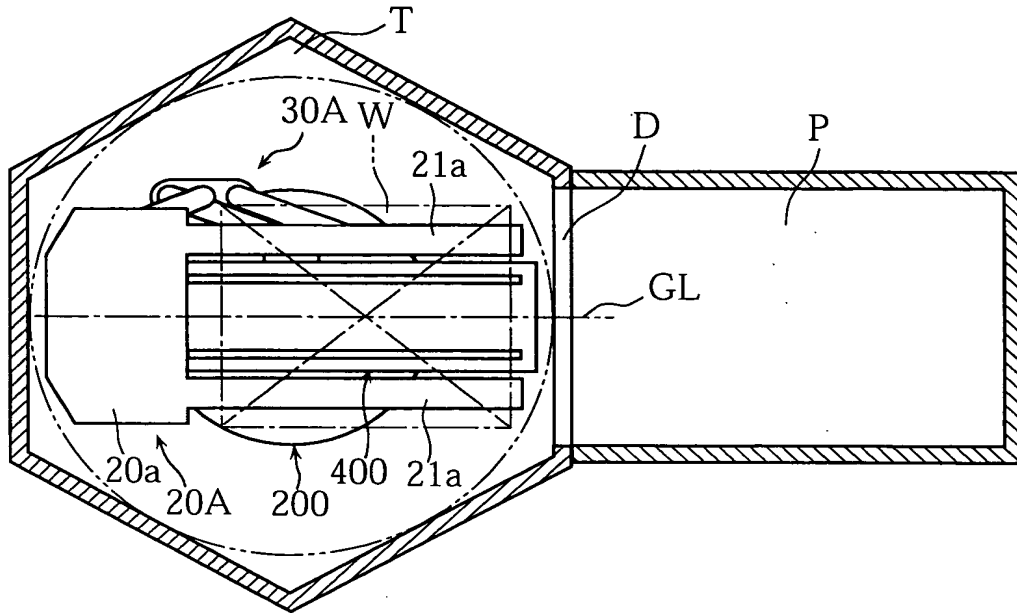


FIG.30B

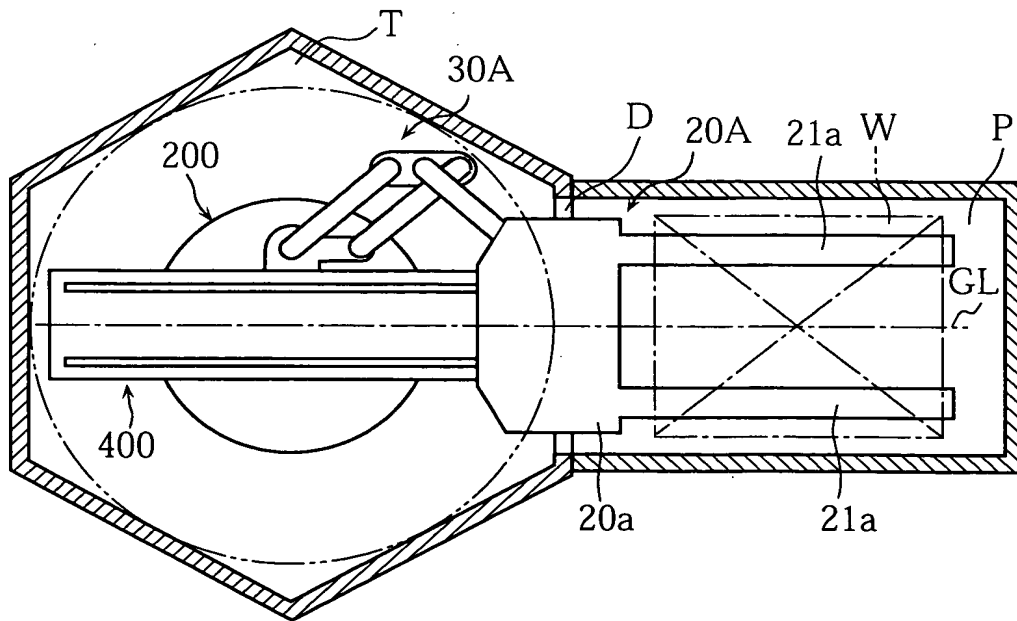




FIG.32

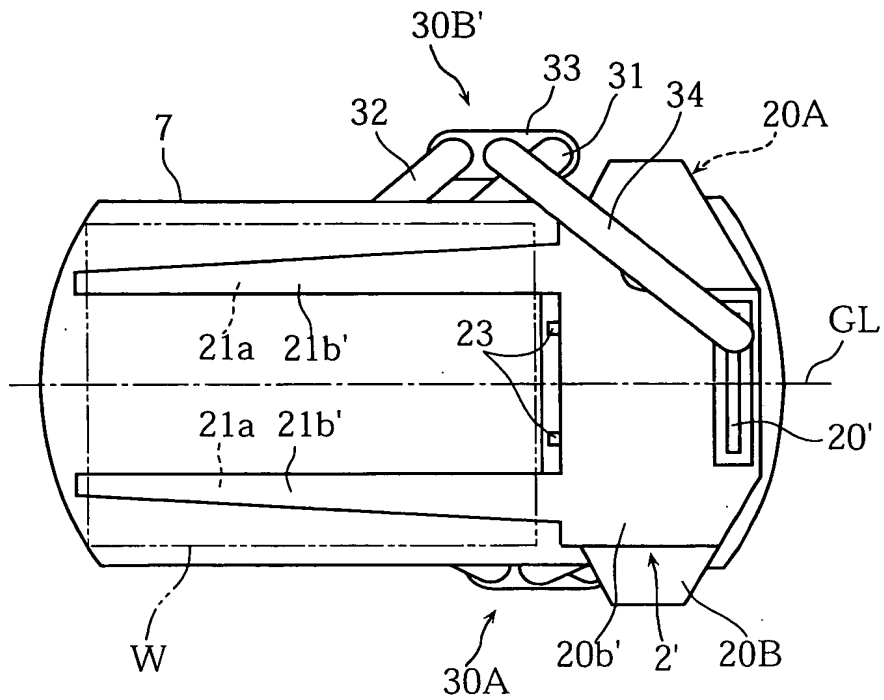


FIG.33

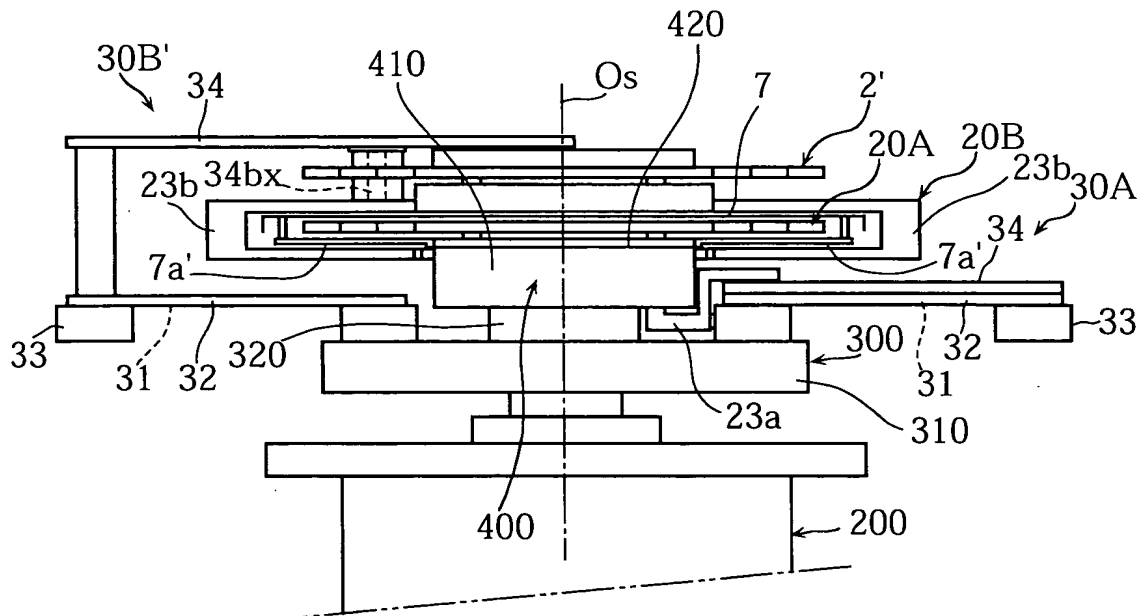


FIG.34A

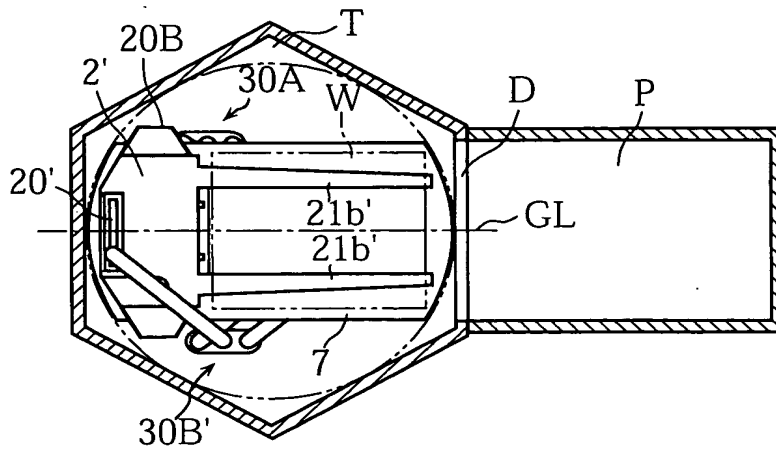


FIG.34B

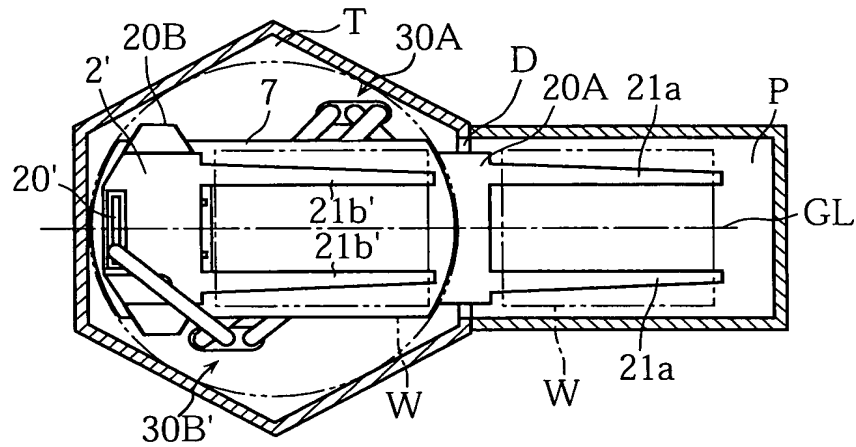


FIG.34C

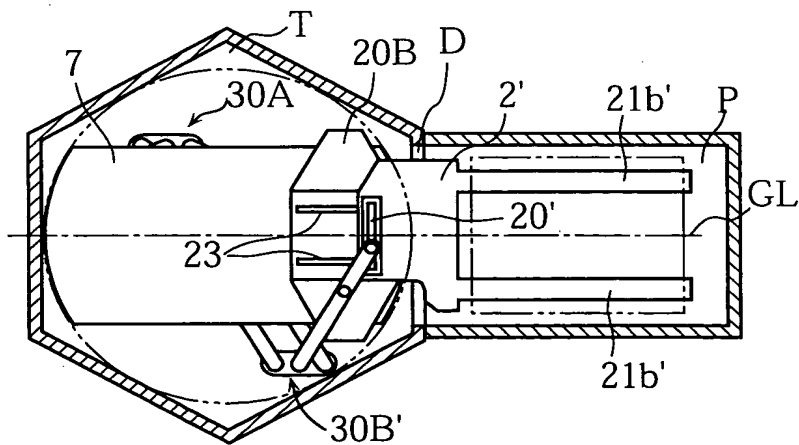




FIG.35C  
後退位置

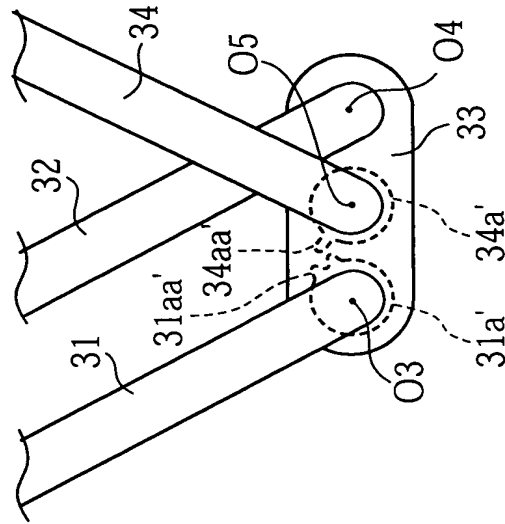


FIG.35B  
思案点付近

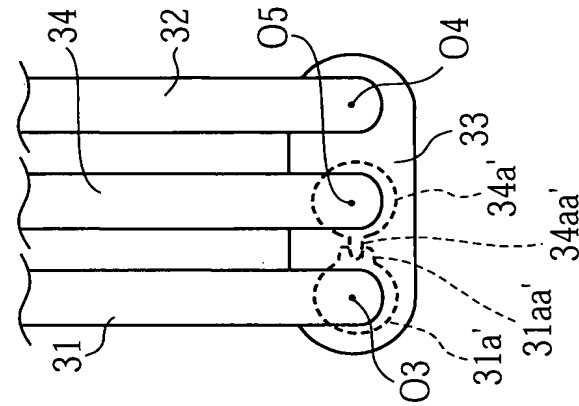


FIG. 35A  
前進位置

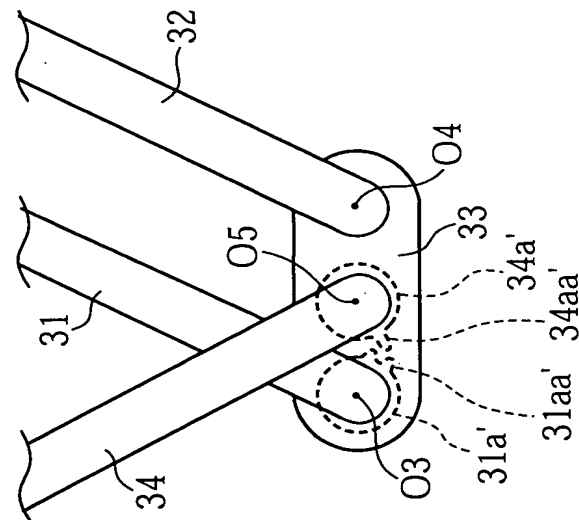


FIG.36  
関連技術

